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EE6007 MICRO ELECTRO MECHANICAL SYSTEMS

DETAILED SYLLABUS

OBJECTIVES

- To provide knowledge of semiconductors and solid mechanics to fabricate MEMS devices.
- To educate on the rudiments of Micro fabrication techniques.
- To introduce various sensors and actuators
- To introduce different materials used for MEMS
- To educate on the applications of MEMS to disciplines beyond Electrical and Mechanical engineering.

UNIT I INTRODUCTION

Intrinsic Characteristics of MEMS – Energy Domains and Transducers- Sensors and Actuators – Introduction to Micro fabrication - Silicon based MEMS processes – New Materials – Review of Electrical and Mechanical concepts in MEMS – Semiconductor devices – Stress and strain analysis – Flexural beam bending- Torsional deflection.

UNIT II SENSORS AND ACTUATORS-I

Electrostatic sensors – Parallel plate capacitors – Applications – Interdigitated Finger capacitor – Comb drive devices – Micro Grippers – Micro Motors - Thermal Sensing and Actuation – Thermal expansion – Thermal couples – Thermal resistors – Thermal Bimorph - Applications – Magnetic Actuators – Micromagnetic components – Case studies of MEMS in magnetic actuators- Actuation using Shape Memory Alloys

UNIT III SENSORS AND ACTUATORS-II

Piezoresistive sensors – Piezoresistive sensor materials - Stress analysis of mechanical elements – Applications to Inertia, Pressure, Tactile and Flow sensors – Piezoelectric sensors and actuators – piezoelectric effects – piezoelectric materials – Applications to Inertia, Acoustic, Tactile and Flow sensors.

UNIT IV MICROMACHINING

Silicon Anisotropic Etching – Anisotrophic Wet Etching – Dry Etching of Silicon – Plasma Etching – Deep Reaction Ion Etching (DRIE) – Isotropic Wet Etching – Gas Phase Etchants – Case studies - Basic surface micro machining processes – Structural and Sacrificial Materials – Acceleration of sacrificial Etch – Striction and Antistriction methods – LIGA Process - Assembly of 3D MEMS – Foundry process.

UNIT V POLYMER AND OPTICAL MEMS 9

Polymers in MEMS– Polimide - SU-8 - Liquid Crystal Polymer (LCP) – PDMS – PMMA – Parylene – Fluorocarbon - Application to Acceleration, Pressure, Flow and Tactile sensors- Optical MEMS – Lenses and Mirrors – Actuators for Active Optical MEMS.

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TEXT BOOKS:

1. Chang Liu, "Foundations of MEMS", Pearson Education Inc., 2006.

2. Stephen D Senturia, "Microsystem Design", Springer Publication, 2000.

3. Tai Ran Hsu, "MEMS & Micro systems Design and Manufacture" Tata McGraw Hill, New Delhi, 2002.

REFERENCES:

1. Nadim Maluf, "An Introduction to Micro Electro Mechanical System Design", Artech House, 2000.

2. Mohamed Gad-el-Hak, editor, "The MEMS Handbook", CRC press Baco Raton, 2000

3. Julian w. Gardner, Vijay K. Varadan, Osama O. Awadelkarim, "Micro Sensors MEMS and Smart Devices", John Wiley & Son LTD,2002

4. James J.Allen, "Micro Electro Mechanical System Design", CRC Press Publisher, 2010

5. Thomas M.Adams and Richard A.Layton, "Introduction MEMS, Fabrication and Application," Springer 2012.

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